

Application No. 10/766,474
Response dated January 29, 2009
to Office Action mailed October 2, 2008

AMENDMENTS TO THE SPECIFICATION

Please replace the Abstract of the disclosure, beginning on page 16 of the as-filed specification, with the following amended Abstract:

A method for manufacturing a substrate with a first plasma processing system having preconditioned components. The method comprises obtaining a component of a plasma processing system that has been coated with a film of material in a plasma processing chamber of a second plasma processing system different than the first plasma processing system, disposing the component in a plasma processing chamber of the first plasma processing system, disposing the substrate on a chuck in the plasma processing chamber of the first plasma processing system, and forming a plasma in a processing region within the plasma processing chamber of the first plasma processing system.

A clean copy of the amended Abstract is provided below:

A method for manufacturing a substrate with a first plasma processing system having preconditioned components. The method comprises obtaining a component of a plasma processing system that has been coated with a film of material in a plasma processing chamber of a second plasma processing system different than the first plasma processing system, disposing the component in a plasma processing chamber of the first plasma processing system, disposing the substrate on a chuck in the plasma processing chamber of the first plasma processing system, and forming a plasma in a processing region within the plasma processing chamber of the first plasma processing system.